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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: TETSUKA et al

Serial No.: 10/784,275

Filed: February 24, 2004

For: Plasma Processing Apparatus And Plasma  
Processing Method

Art Unit: 1763

Examiner: R. Zervigon

**AMENDMENT**

Mail Stop: Amendment (No Fee)  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

July 19, 2006

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application, in response to the Office Action dated April 20, 2006. The amendments are listed below and set forth on the following pages.

Amendments to the Specification;

Amendments to the Claims;

Amendments to the Drawings describing changes to drawing shown in the Appendix;

Remarks are included following the amendments; and

An Appendix including amended drawing figures is attached following the

Remarks